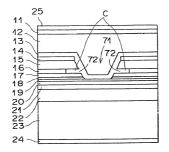
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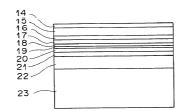
F I G.1A



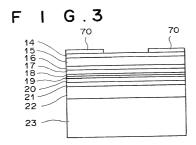
F | G.1B



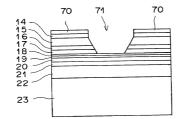
F I G.2



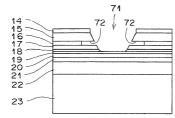
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F I G.4

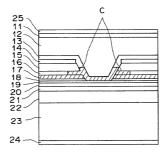


F I G.5



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F I G.6A

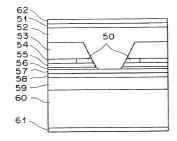


F I G.6B



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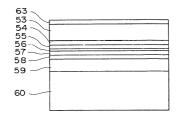
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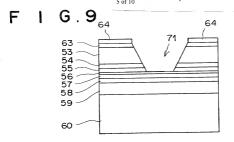
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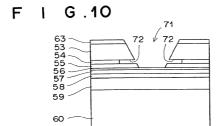


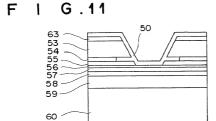
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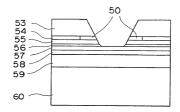
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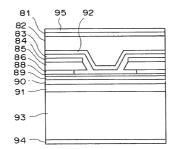




## F I G.12



F I G.13A

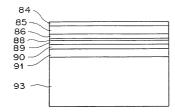


F I G.13B

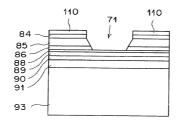


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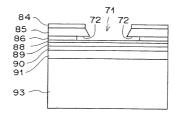
F I G.14



F I G.15

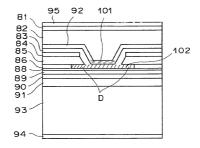


F I G.16



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F I G.17A

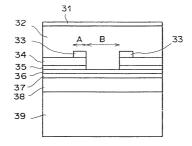


F I G.17B



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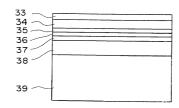
## F I G.18A



F I G.18B

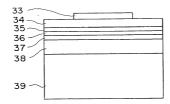


F I G.19

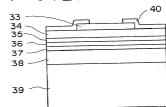


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F I G.20



F I G.21



F I G.22

